



## Jon M. Hiller

Scientific Associate

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## Biography

I assist and train scientists and graduate students how to operate the Zeiss 1540XB Focused Ion Beam (FIB) system as well as the JEOL 4000 High Resolution TEM. My present focus is in developing new FIB techniques for nanoscale pattern generation and advanced site specific TEM preparation.

## Scientific Interests

- Refining and developing preparation techniques for TEM using Focused Ion Beams.
- In situ nanomanipulation
- Direct write lithography for MEMS prototyping
- TEM stage development

## Interests and Hobbies

- Fishing
- Hiking
- Woodworking
- Watching the Green Bay Packers beat the Chicago Bears ;)